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# The Application of Nanotechnology methods for Manufacturing of a Plate of a Pendulous Accelerometer

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*The issues of nanotechnological maintenance of indicators of the quality of the plates of pendulous accelerometers are considered. The application of two-side lapping with bounded abrasive to provide the required flat-parallelism of plates is justified. The possibility to form the ledges and hollows as parts of the design of the plate, by the method of plasma-chemical etching is shown. The procedure of ensuring the uniform thickness of thin film coatings, which are used as the mask for the plasma-chemical etching, is suggested.*

**Keywords:** *pendulous accelerometer, quartz plate, lapping, plasma-chemical etching, plasma evaporation, magnetron sputtering.*

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